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Comparison of Single-Event Transients in an Epitaxial Silicon Diode Resulting from Heavy Ion-, Focused X-Ray- and Pulsed Laser-Induced Charge Generation

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This work was supported in part by the Defense Threat Reduction Agency through its Basic Research program grant HDTRA1-16-1-0007, Sandia National Lab's LDRD program, and NASA Grand and Cooperative Agreement 80NSSC20K0424.

Acronyms and Disclaimers



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Argonne National Lab	ANL
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Lawrence Berkley National Lab	LBNL
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Linear Energy Transfer	LET
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U.S. Naval Research Lab	NRL
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Single Event Effect	SEE
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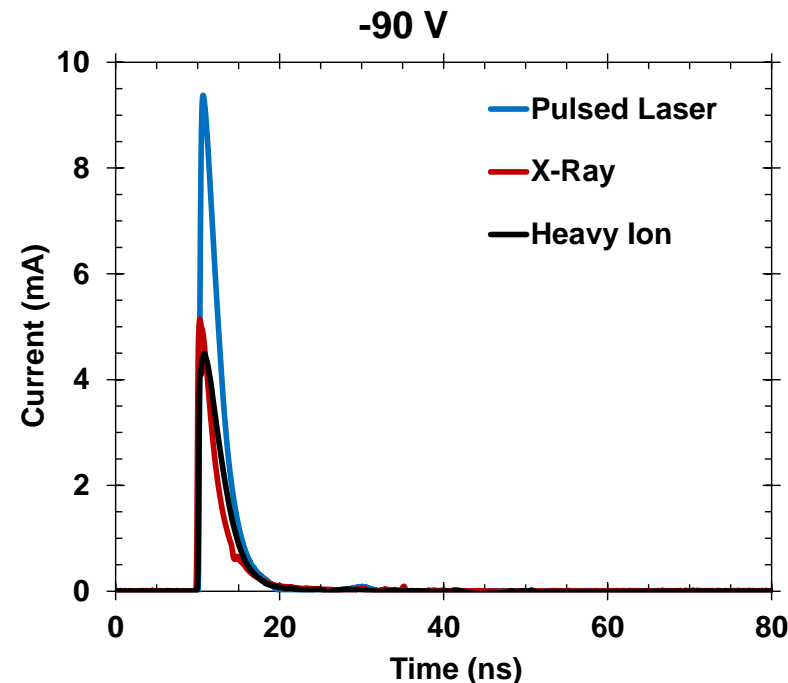
Single Event Transient	SET
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Sensitive Volume	SV
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Total Ionizing Dose	TID
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1. A variety of charge generation methods are now used in SEE testing
2. Different SET shape characteristics observed from different sources ★
3. Proposed mechanisms, implications for alternative SEE testing methods



Comparison of Charge Generation Sources for SEE Testing



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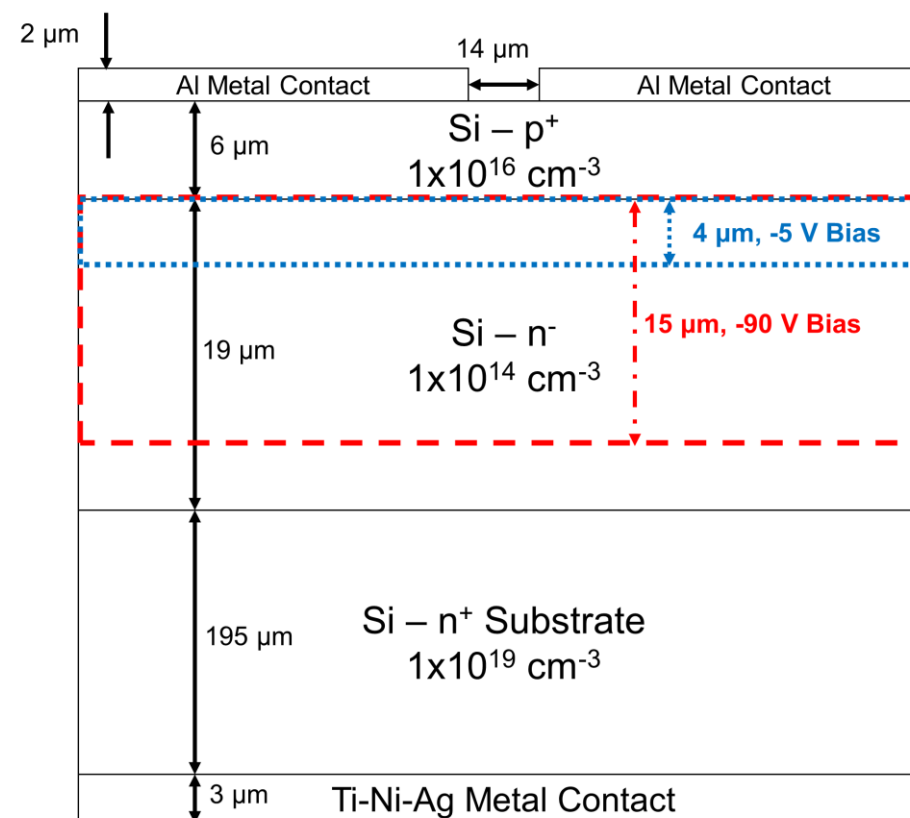
Source	Heavy Ions	Pulses Laser	Focused X-Ray
Known correlation to the space radiation environment	✓	✗	✗
Facility accessibility in U.S.	Few	Many	Few
Spatial, temporal control over charge generation	✗	✓	✓
No accumulation of TID	✗	✓	✗
Penetration of metals	✓	✗	✓

Experimental Conditions



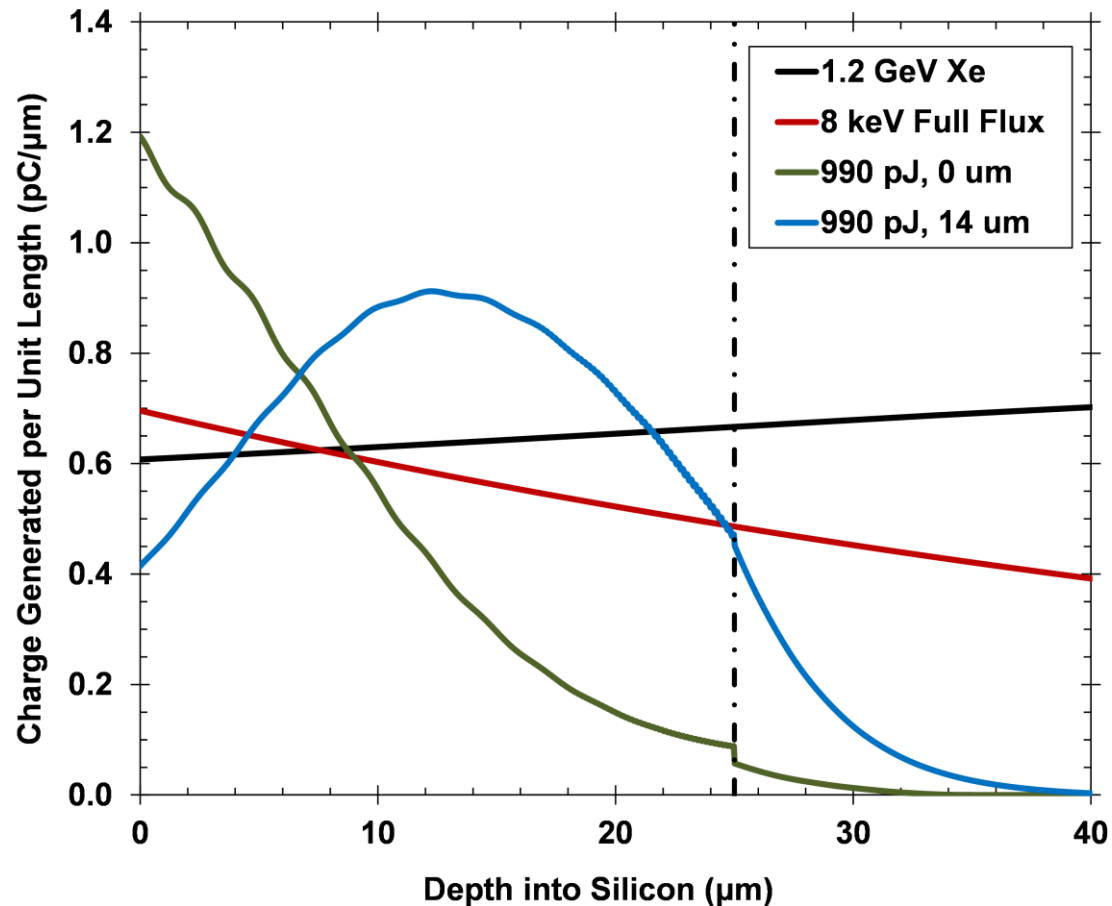
- Heavy Ion SET Testing:
 - LBNL 88" Cyclotron facility
 - 3 LETs from 10 MeV/amu cocktail
- Focused X-Ray SET Testing:
 - ANL Advanced Photon Source
 - 8, 10, and 12 keV photon energies
- TPA Laser SET Testing:
 - NRL Ultrafast Laser Facility
 - 400, 750, and 990 pJ

- **Different electric field strengths, depletion region thicknesses**



K. L. Ryder *et. al.*, IEEE TNS vol. 67, no. 1

Charge Generation Profiles and Calculations



- **Heavy Ions:**

- $Q_{gen,ion} = \frac{\rho}{E_{ehp}} \int_l LET(x) dx$

- <1 μm radial, 10s – 100 μm lateral

- **Picosecond Focused X-Ray:**

- $Q_{gen,x-ray} = \frac{E_p}{E_{ehp}} (1 - e^{-\alpha l})$

- ~1 μm radial, 10s – 100 μm lateral

- **Femtosecond Pulsed Laser:**

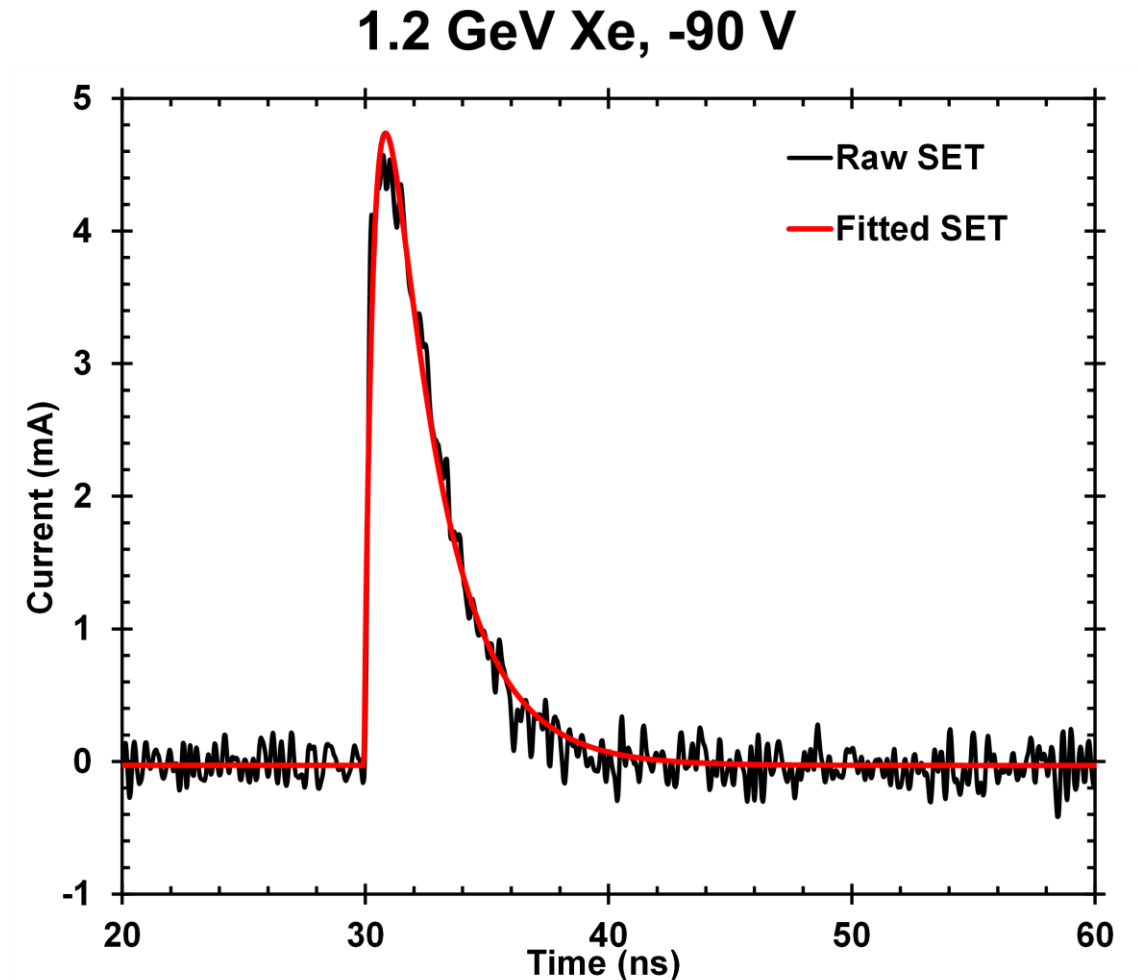
- Lumerical FDTD Solutions
 - ~1 μm radial, ~10s μm lateral

Transient Shape and Data Analysis

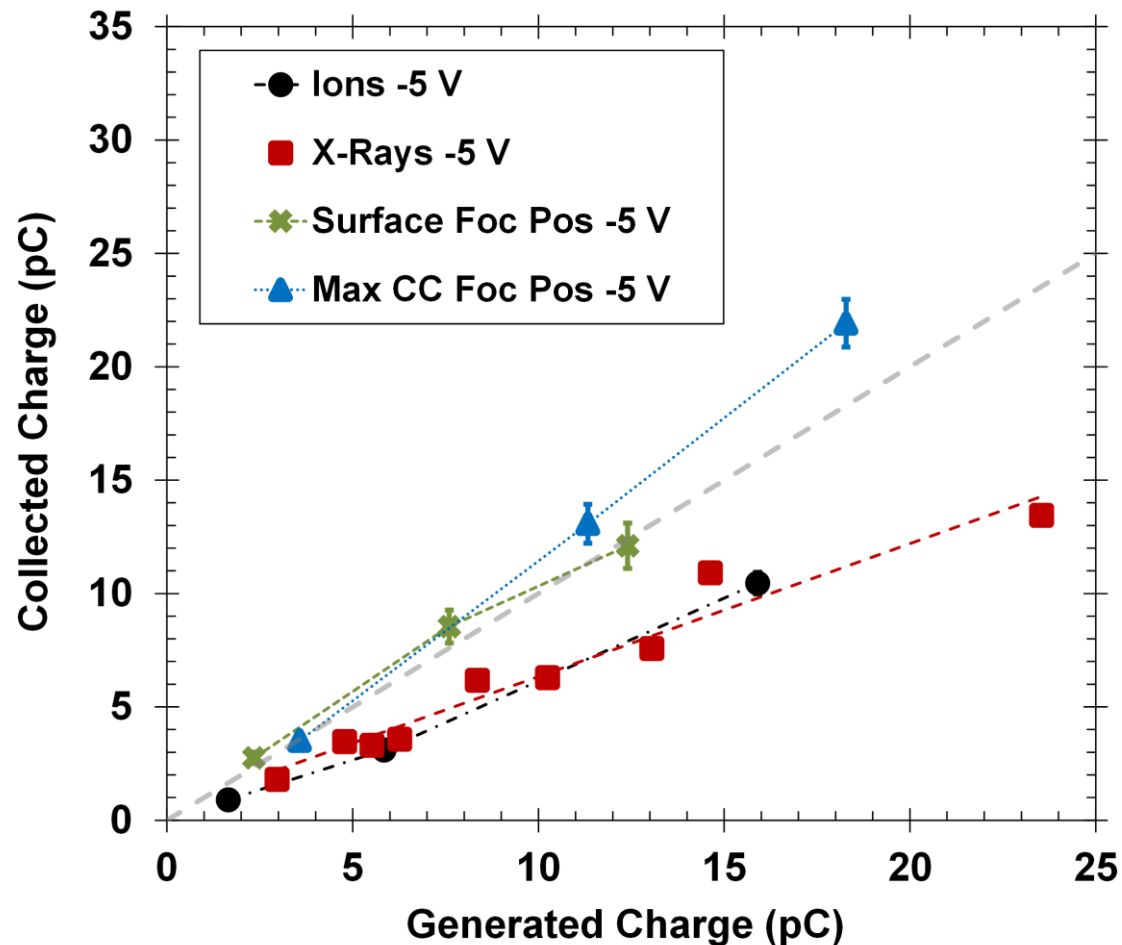


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- $$f(t) = \begin{cases} 0, & t < a \\ I \left(e^{-\tau_1(t-a)} - e^{-\tau_2(t-a)} \right), & t \geq a \end{cases}$$
- SET characteristics found using fitted SETs
- SET Characteristic Calculations:
 - Collected charge – integral
 - Transient rise time – from 1% to peak
 - *Transient fall time – from peak to 1%*

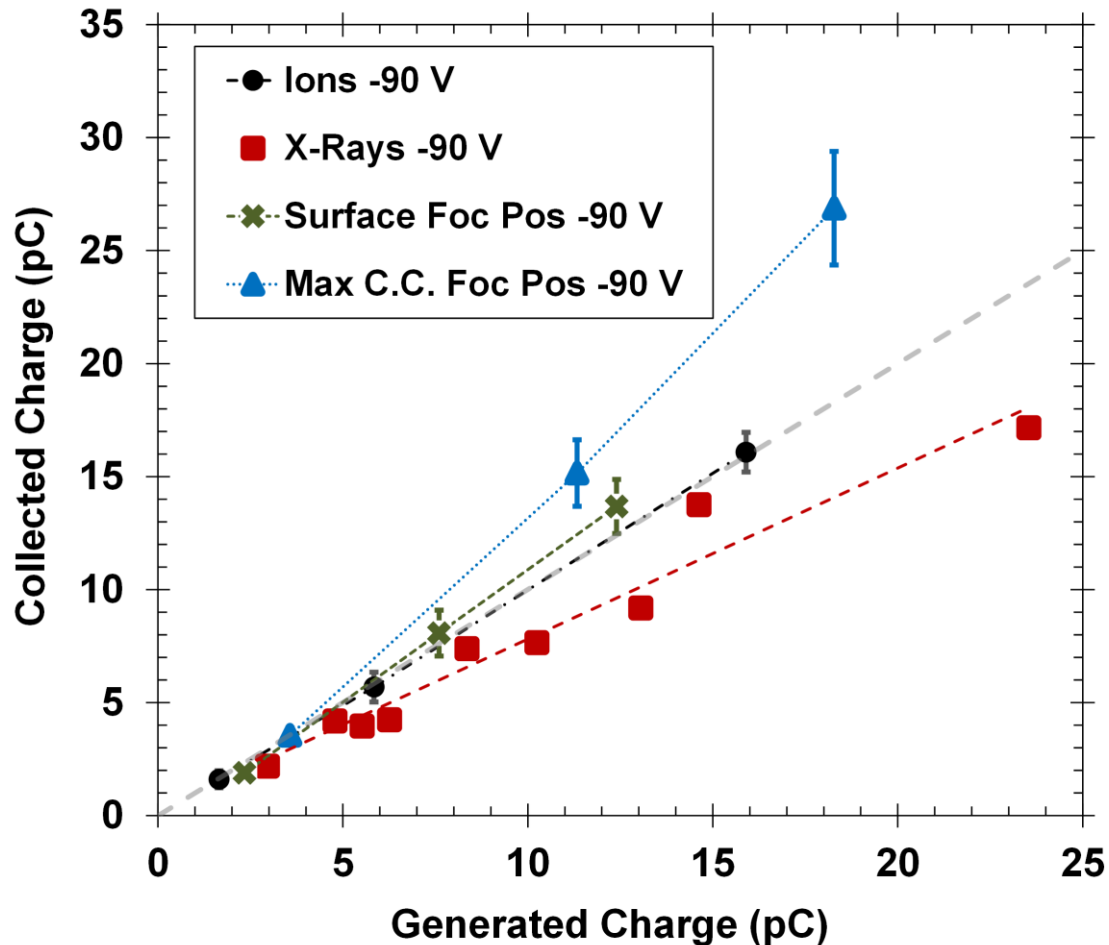


Collected Charge from -5 V Experiments



- Collection Efficiency, $Q_{eff} = \frac{Q_{out}}{Q_{in}}$
 - $Q_{eff} \propto$ Sensitive volume (SV)
 - Laser collection efficiencies $\sim 1, 1.2$
 - Active region = Laser-induced SV
 - Ion, x-ray collection efficiencies ~ 0.6
 - Active region $>$ Ion-, x-ray-induced SV
- Larger SV indicates more funneling
 - Laser-induced potential modulation $>$ Ion-, x-ray-induced potential modulation

Collected Charge from -90 V Experiments



- Collected charge, Q_{eff} increase \propto Increase in SV over -5 V SVs

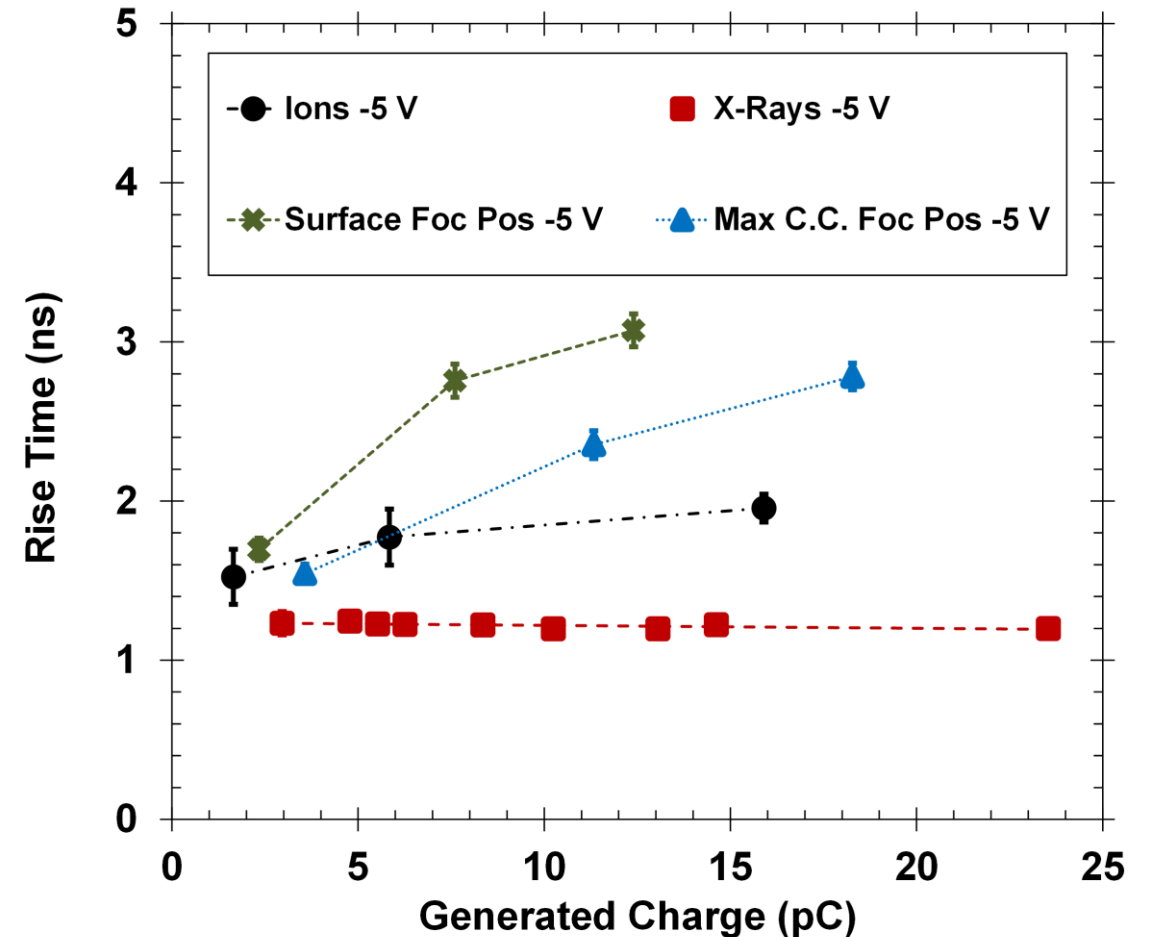
	-5 V Q_{eff}	-90 V Q_{eff}	% Increase
Ions	0.6	1.0	67
Lasers	1, 1.2	1.1, 1.4	10, 17
X-Rays	0.6	0.8	33

- Changes in SV relate to funneling
 - Ion SVs – standard funneling
 - Laser SVs – fully depleted device
 - X-ray SVs – less funneling

Transient Rise Time from -5 V Experiments



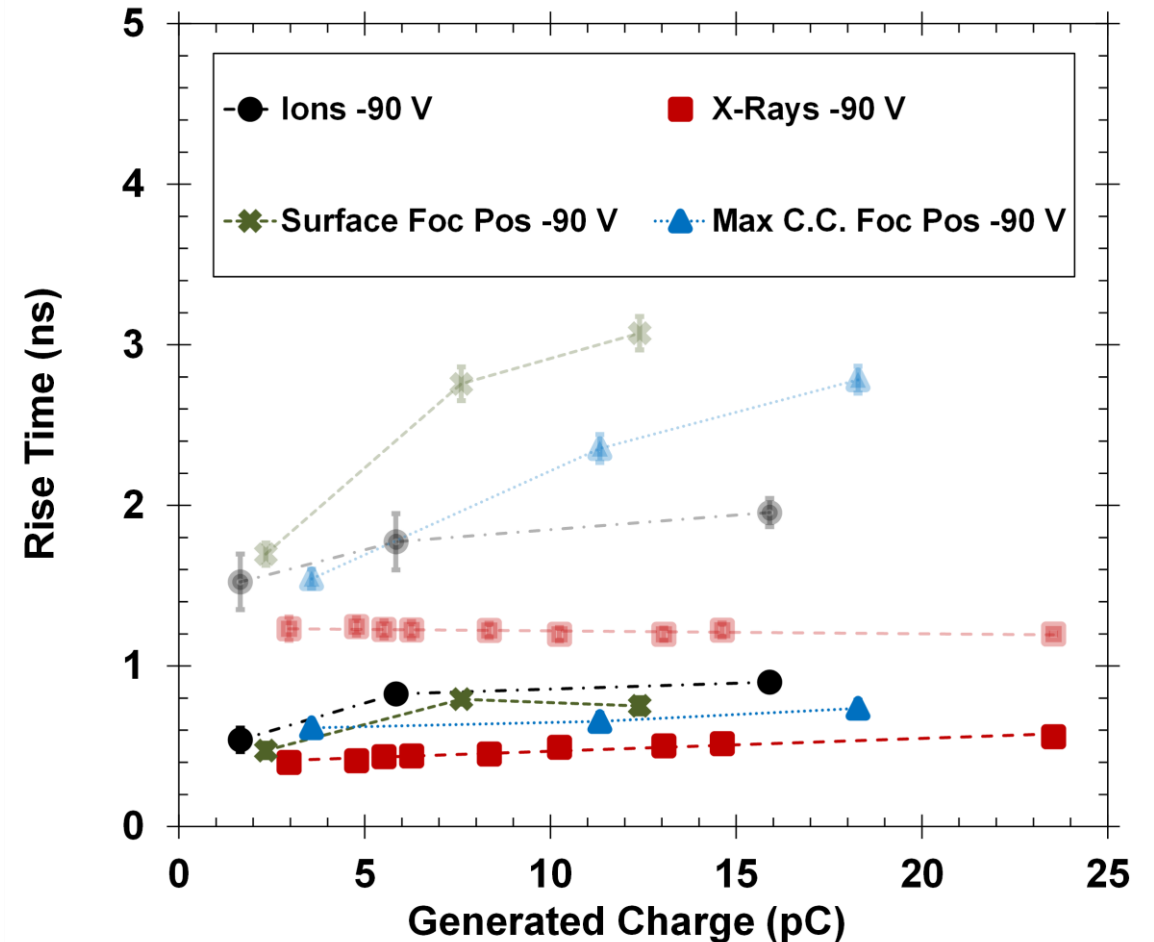
- Dominated by drift \propto Electric field strength
- Ion, laser rise time increases with generated charge
 - Changes in carrier density cause different perturbations in electric field
- X-ray rise time independent of generated charge
 - X-rays cause less perturbations in electric field compared to ions, lasers



Transient Rise Time from -90 V Experiments



- **More consistency** → **Stronger electric field dominates response**
 - Faster rise times compared to -5 V
 - Less variation with generated charge
- Transient rise times follow SVs
 - X-ray – smallest SVs, fastest rise times
 - Ion – medium SVs, medium rise times
 - Laser – largest SVs, slowest rise times





SET shape in an epitaxial silicon diode depends on source

Heavy Ions	Q_{eff} increases with increased reverse bias	Transient rise time <u>dependent</u> on charge generated	<u>Medium</u> funneling, perturbations in electric field
Pulsed Laser	Q_{eff} is larger than ions', changes less with bias	Transient rise time <u>dependent</u> on charge generated	<u>Maximum</u> funneling, perturbations in electric field
Focused X-Ray	Q_{eff} is smaller than ions', changes less with bias	Transient rise time <u>independent</u> on charge generated	<u>Minimum</u> funneling, perturbations in electric field